

Notice of References Cited

Application/Control No.

10/583,965

Applicant(s)/Patent Under

Reexamiration

YEE ET AL.

Examiner

Alicia M. Harrington

Art Unit

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Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2004/0263967	12-2004	Kwon et al.	359/456
*	B	US-2004/0125048	07-2004	Fukuda et al.	345/030
*	C	US-2003/0002160	01-2003	Johnson et al.	359/619
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	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Miao He; Reflow technique for the fabrication of an elliptical microlens array in sol-gel material; 20 December 2003; Applied Optics Vol. 42 NO. 36.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.